

ABSTRACT

A module for use in a process tool is disclosed. The module comprising an enclosure for housing a device to be tested; and a frame coupled to the enclosure. The frame includes a standard interface to the process tool and a kinematic interface to the enclosure to facilitate
5 repeatable and high accuracy docking of the enclosure. These could be inspection components, measurement devices or other forms of instrumentation that are used for gathering information and/or analyzing data. The equipment could be used for, but not limited to, the fabrication of substrates, including semiconductor devices, reticles, and other products.